

1. Record Nr.	UNINA9910711191203321
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Titolo	Semiconductor measurement technology : the results of an interlaboratory study of ellipsometric measurements of thin film silicon dioxide on silicon / / Barbara J. Belzer, David L. Blackburn
Pubbl/distr/stampa	Gaithersburg, MD : , : U.S. Dept. of Commerce, National Institute of Standards and Technology, , 1997
Descrizione fisica	1 online resource
Collana	NIST special publication ; ; 400-99
Altri autori (Persone)	BelzerBarbara J BlackburnDavid L
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	1997. Contributed record: Metadata reviewed, not verified. Some fields updated by batch processes. Title from PDF title page.
Nota di bibliografia	Includes bibliographical references.